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(12) **ABSTRACT OF INVENTION**

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(54) **METHOD FOR MEASURING SURFACE RELIEF BY MEANS OF SCANNING PROBE TYPE MICROSCOPE**

(57) Abstract:

FIELD: electronic measuring technique, namely probe type scanning microscope. SUBSTANCE: method is realized due to use of surface features as reference points at making motions. Motions are performed from one reference point to another adjacent reference point in order to form chain of features arranged one relative to another. Identifying program performs searching, detection and calculation of position coordinates of feature (reference point).

Scanning of comparatively small area around each feature and placing of corresponding fragments of surface according to respective positions allow to construct actual relief of surface. Information related to position coordinates of features and their arrangement system allow to perform precision positioning of probe. EFFECT: enhanced accuracy and linearity at measuring surface relief, improved precision positioning of probe and resolution of instrument. 3 cl, 15 dwg

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